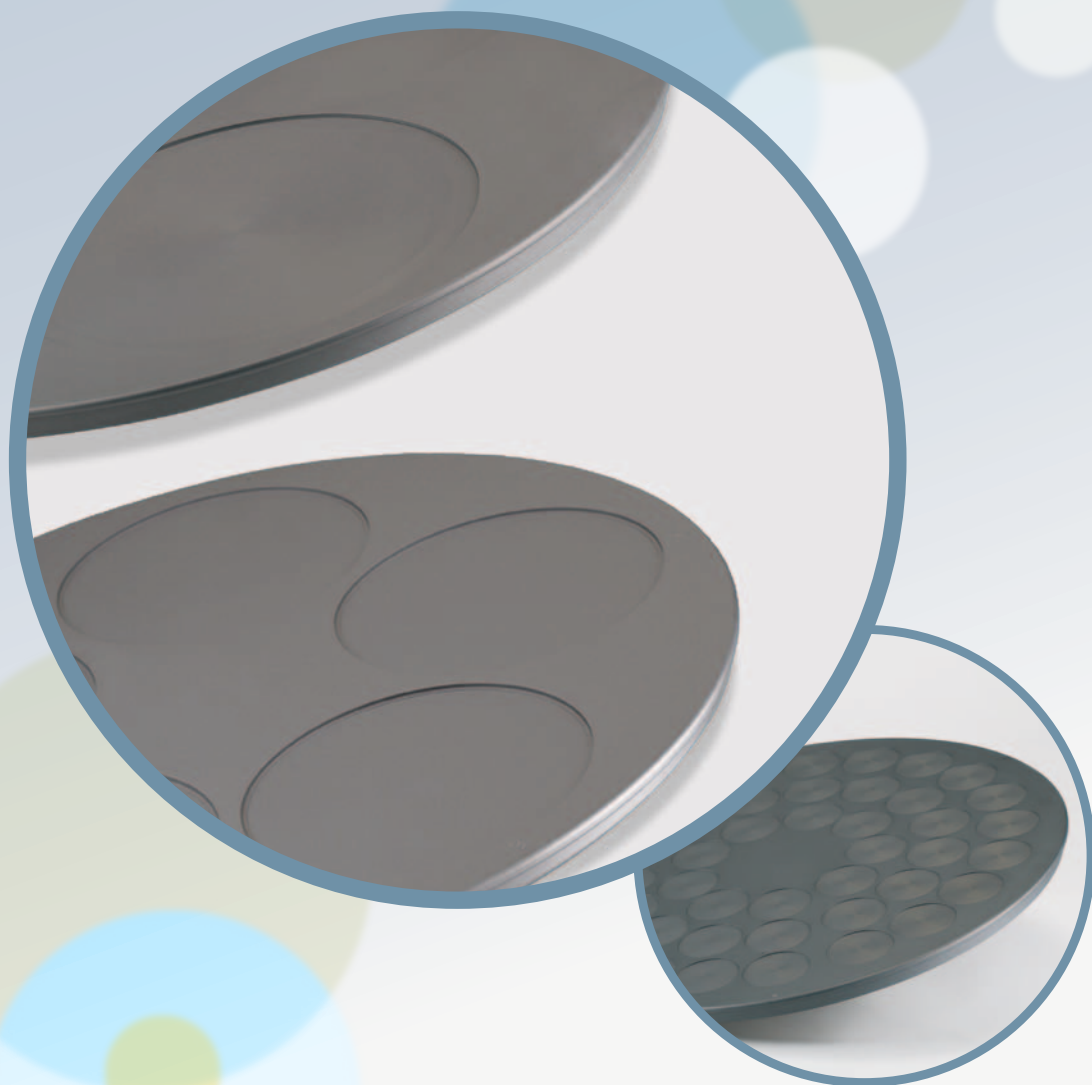


# WAFER CARRIERS FOR MOCVD

HIGH PURITY COATED GRAPHITE

PRODUCT



MERSEN

## MERSEN in the Semiconductor industry:

**Beyond the development of the silicon semiconductor industry, the compound semiconductor has opened a new range of electronic applications.**

A couple years ago, one could find compound semiconductors in limited number of devices like GaAs RF transistors, small LED displays, laser diodes, optical receivers and transmitters. Today, Compound semiconductor growth is driven by mass applications: LED lighting, Flat panel displays, Power electronics, Concentrated PV.

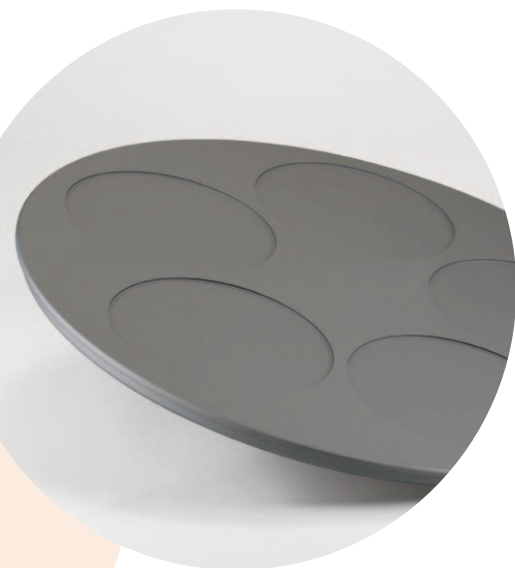
Mersen traditionally supplies high quality coated isotropic graphite parts to OEMs and after-market customers in the electronics industry, including single crystal growing furnaces, epitaxy reactors, MOCVD reactors, dry etchers, ion implanters, and many more.

## A strong expertise and know-how for epitaxy & MOCVD

For more than 20 years, our Bay City and Midland facilities in Michigan USA supply major Silicon and Compound semiconductor chip manufacturers with high purity coated graphite consumables for epitaxial processing:

### Products :

- Wafer carrier
- Susceptor
- Planet
- Satellite
- Platter
- Barrel
- Single wafer



Wafer carrier



Planet

Satellite

# MATERIAL EXPERTISE

To grow highly defined interfaces between individual epitaxial layers, MOCVD process engineers rely on quick and tunable temperature transitions of their process: High speed ramp-up and cool-down cycles of the wafer carrier should be regulated either through inductive or radiative heating with an extreme precision.

## High purity iso-molded graphite

Mersen is a leading specialty iso-molded graphite manufacturer, with two major production facilities located in St Marys PA (USA) and Chongqing (China).

Our graphite grades are engineered to fit the application. Mersen optimizes the thermo-physical properties of its graphite grades to withstand the operating constraints of most existing MOCVD tools:

- Bear fast radiative heating cycles without cracking
- Ensure temperature uniformity on a large scale
- Guarantee a long term integrity of the protective coating
- Avoid any contamination processing high purity graphite



Large cold isostatic press St Marys PA

Typical impurities in SiC coating measured with our in house ETV-ICP-OES

Elements	Concentration ppm	Detection limit ppm
P	0.05	0.03
S	0.1	0.02
As	ND	0.04
Sn	ND	0.04
Zn	0.01	<0.005
Cr	0.03	0.02
W	ND	0.02
Si	MATRIX	0.02
Te	ND	0.08
Pb	ND	0.032
Cd	ND	<0.005
Co	ND	0.006
Ni	0.006	0.005
Fe	0.06	0.02
B	0.48	0.01
Mn	ND	<0.005
Hf	ND	<0.005
Ge	ND	0.006
Ta	ND	0.007
Mg	0.03	<0.005
Mo	0.08	0.011
V	ND	<0.005
Be	ND	<0.005
Cu	0.05	<0.005
Ag	ND	<0.005
Ti	ND	<0.005
Zr	ND	<0.005
Ca	ND	0.025
Al	0.08	0.007
Ga	ND	0.006
Ba	ND	<0.005
Na	0.05	0.016
Li	ND	<0.005
K	ND	0.026

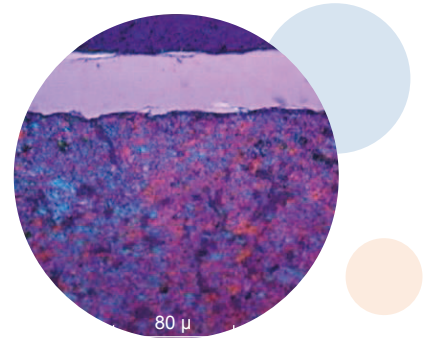
ND : Not Detectable

## High purity CVD coating

Because the properties of its high purity isotropic graphite are uniform and repeatable, Mersen has been able to develop **high integrity protections, suitable for MOCVD.**

Our graphite carriers are processed in a **clean room environment** to avoid surface contamination and get ultra-clean coatings.

- Pyrocarbon coating for GaAs epitaxy
- SiC coating for GaN epitaxy
- TaC coating for SiC epitaxy



SiC layer on iso graphite

Data herein contained are provided for general information purpose only and are not binding. Mersen shall have no liability whatsoever with respect to information contained herein. Duplication, reproduction or translation of any information contained herein, in whole or in part, is strictly prohibited without prior written consent of Mersen. Our materials are in conformity with the RoHS-Directive (Restriction of the use of certain Hazardous Substances in electrical and electronic equipment). Besides Mersen guarantees the application of the European Community REACH-Regulation (Registration, Evaluation, Authorization and Restriction of Chemical substances) to all its plants located in Europe. We are constantly involved in engineering and development. Accordingly, Mersen reserves the right to modify, at any time, the technology and product specifications contained herein.

# MERSEN, YOUR PARTNER TO REDUCE THE TOTAL COST OF OWNERSHIP OF YOUR PROCESS

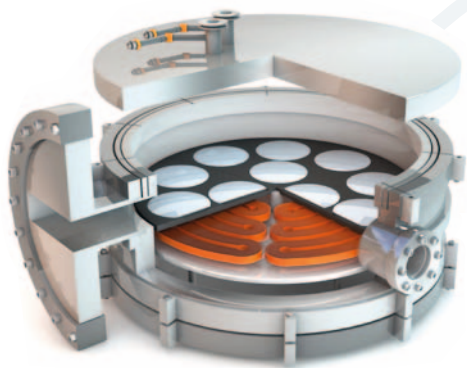
Your goal is the optimization of a highly complex system combining:

- The wafer
- The graphite wafer carrier
- The MOCVD machine

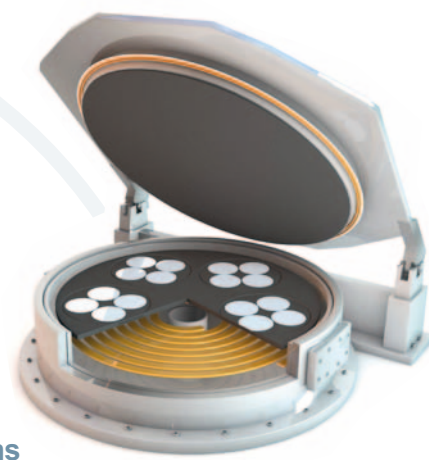
Mersen develops long term partnerships with semiconductor manufacturers by supporting their R&D and production efforts.

## MOCVD systems and processes:

Inductive or radiative heating  
Temperature of process  
Ramp up and cool down cycles  
Etching



MOCVD machine using radiative heating



MOCVD system using inductive heating

## Mersen Partnership

### OUR SERVICES AND COMMITMENTS :

- Quick turnaround of your R&D designs
- Custom pocket designs
- Multiple pocket designs within one carrier to speed up R&D
- Critical dimensions report provided with each carrier

## WAFER CARRIER:

High precision pocket profiles  
Repeatable geometries  
Coating uniformity

## WAFER :

Material : Sapphire, SiC, GaAs, Si  
Diameters : 2" to 8"  
Thickness  
Patterning process



## OUR OBJECTIVE

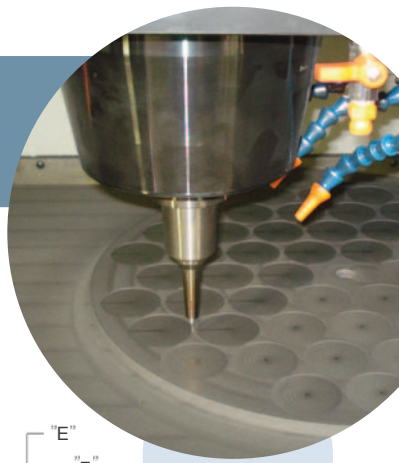
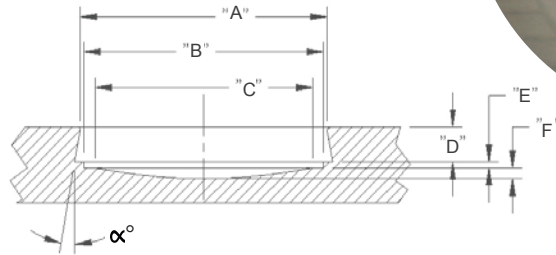
Our objective is to help you to reach the best temperature uniformity:

- Within the pocket
- Pocket to pocket
- Batch to batch, for a long time

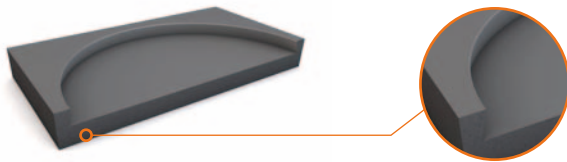
# HIGH PRECISION DESIGN & MACHINING

Mersen has developed a **dedicated CAD and machining process** to manufacture customizable and accurate pocket and susceptor designs.

Our typical machining capability is at  $\pm 5\mu\text{m}$ .

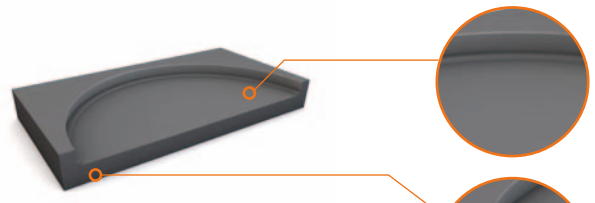


A key engineering topic to reach the **best temperature uniformity**:  
**Customize the pocket designs** to fit with different wafer geometries and thermal behaviours



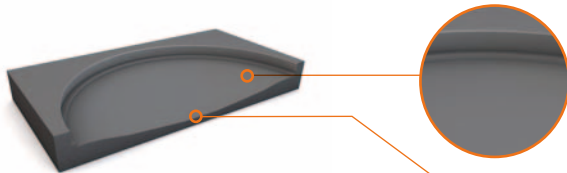
## ■ Flat

Pocket diameter and edge angle  
A dimension  $\pm 0.05$  mm  
 $\alpha$  angle  $\pm 0.1^\circ$  target



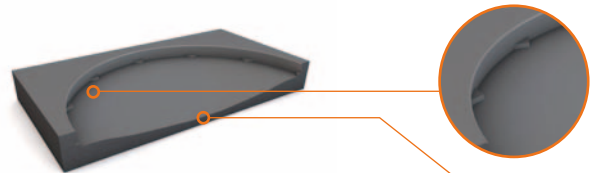
## ■ Rim + Flat

Top of pocket to Rim and Pocket diameter  
D and B dimensions  $\pm 0.025$  mm



## ■ Rim + dish (convex or concave)

Rim height (E dimension)  $\pm 0.007$  mm  
Typical dish (F dimension)  $\pm 0.007$  mm



## ■ Tabs + dish (convex or concave)

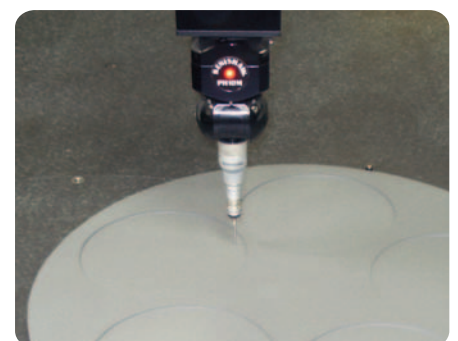
Tabs height (E dimension)  $\pm 0.007$  mm  
Typical dish (F dimension)  $\pm 0.007$  mm

## Quality control and parameters monitoring

All the parts are measured with CMMs, with a precision of  $2.5\mu\text{m}$ , before and after the CVD process.

All the key parameters during the coating runs are recorded and stored for 5 years.

The coating thickness is determined accurately.





**A WORLD EXPERT  
in materials and solutions  
for high temperature processes**

### **A GLOBAL PLAYER**

Global expert in materials and solutions for extreme environments as well as in the safety and reliability of electrical equipment, Mersen designs innovative solutions to address its clients' specific

needs to enable them to optimize their manufacturing process in sectors such as energy, transportation, electronics, chemical, pharmaceutical and process industries.

Contact in North America  
MERSEN USA BN Corp.  
Bay City Branch,  
900 Harrison Street  
Bay City, MI 48708, USA  
Tel.: +1 989 894 29 11  
Fax: +1 989 895 77 40

Contact in North America  
MERSEN USA Midland-MI Inc  
P.O Box 186 - 2927 Venture Drive  
Midland, MI 48640  
USA  
Tél. : +1 989 835 7604  
Fax : +1 989 835 2195

Contact for Europe  
MERSEN France Gennevilliers SAS  
41 rue Jean Jaurès - BP 148  
F-92231 GENNEVILLIERS CEDEX  
FRANCE  
Tel.: +33 (0)1 41 85 45 14  
Fax: +33 (0)1 41 85 43 53

Contact for Asia  
MERSEN Kunshan Co. Ltd.  
#29 South Taihu Road,  
Kunshan Development Zone,  
Kunshan, Jiangsu Province,  
215334, PR CHINA  
Tel.: +86 512 5763 9808  
Fax: +86 512 5763 9811